

Application/Control No. 09/954,287 10/666,120

Applicant(s)/Patent Under Reexamination
NIKOONAHAD ET AL.

Examiner
Richard A Rosenberger

Art Unit
2877

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	C	US-			
	D	US-			
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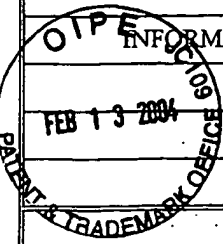
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	N					
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*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.		
				M-10575-2C US		09/760,558 10/666,120		
 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				Applicant(s)				
				MEHRDAD NIKOONAHAD ET AL.				
				Filing Date		Group		
				January 16, 2001		2877		
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
<i>m</i>	AA	Re. 33,991	7/14/92	Shiba et al.	356	237		
<i>m</i>	AB	5,189,481	2/23/93	Jann et al.	356	73		
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		Document	Date	Country	Class	Subclass	Yes	No
	AL							
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	AN							
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	AQ	ISOMET Corporation Specification for LS-55 V Acousto Optic Deflector/AOT, 4 pages						
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Examiner		<i>RAD</i>		Date Considered		3/11/04		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

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	Examiner Richard Rosenberger	Art Unit 2877	Page 1 of 1

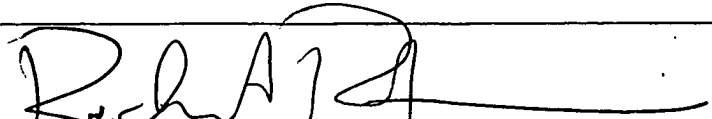
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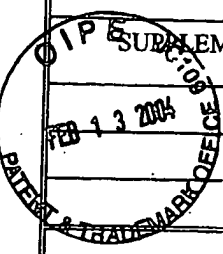
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U.S. Department of Commerce, Patent and Trademark				Atty. Docket No.		Application No.		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				TNCR.001US4		10/666,120		
				Applicant(s)		Conf. No.		
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<i>PH</i>	7	Merry, "High Resolution Acoustooptic Deflector Demonstrated in a Laser Scanner," pp. 32-34.						
<i>AR</i>	8	"All About Bragg Angle Errors in Acousto-Optic Modulators and Deflectors," <i>ISOMET</i> , May 1993, pp. 1-23.						
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TRADEMARK OFFICE

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						Applicant(s)		10/666,120	
						MEHRDAD NIKOONAHAD ET AL.			
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				M-10575-2C US.		09/954,287	
				Applicant(s)		10/1066, 1.10	
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)						M-10575-3C US		09/954,287		
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